Contrast Enhanced White Light Interferometry

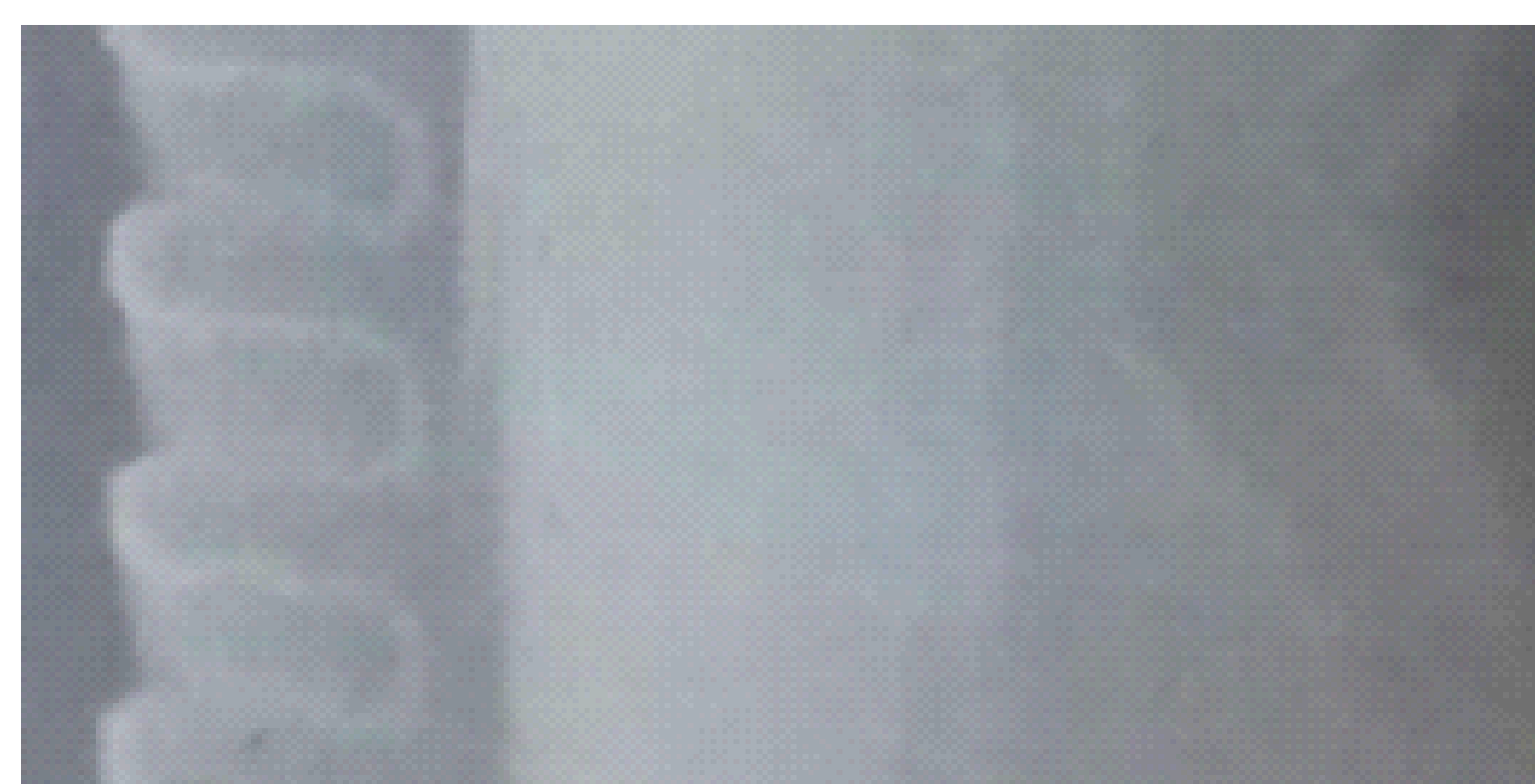## GPGPU's can process images much faster than conventional PC's
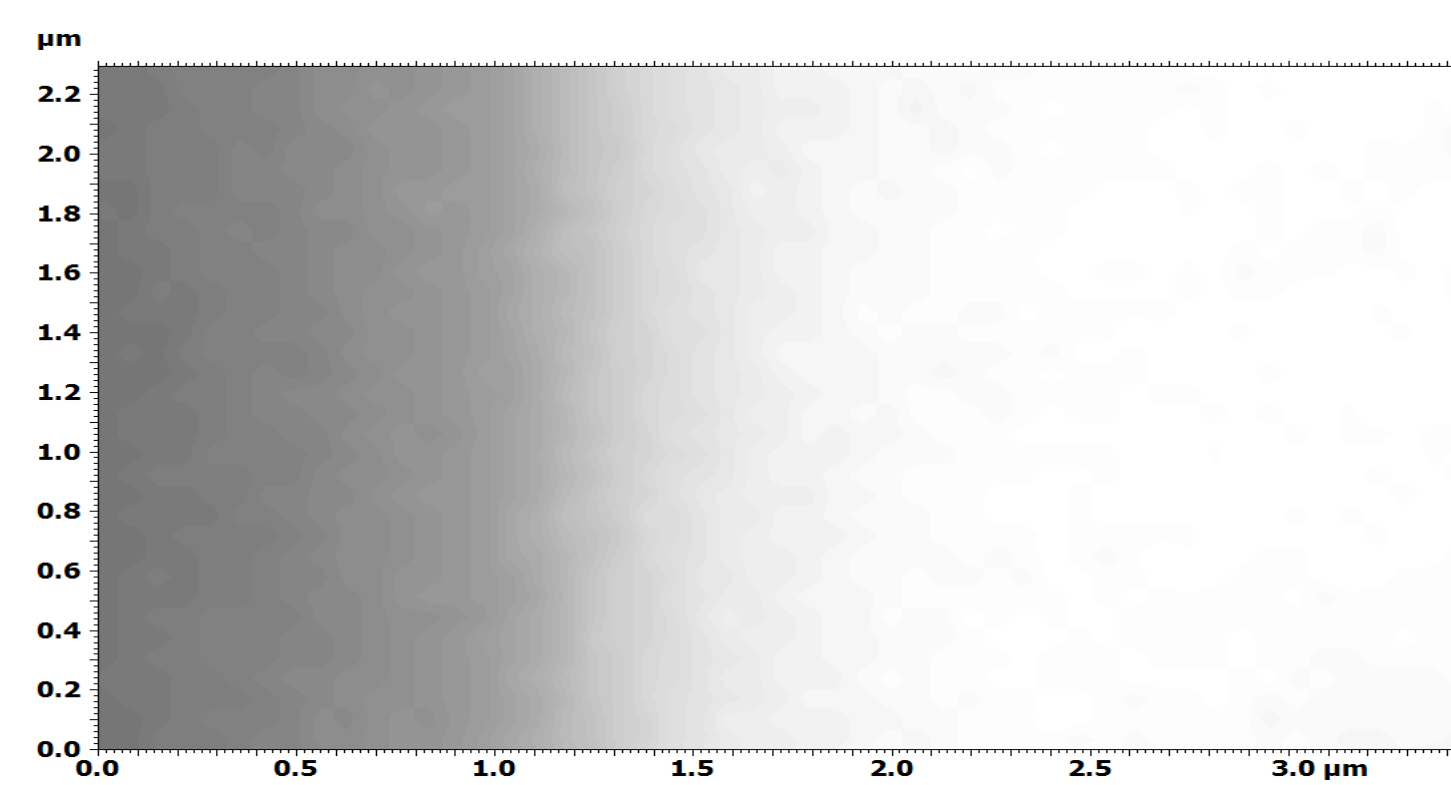
 + = **higher speed + improved results**

advanced algorithms can be used for the image processing based on the higher performance of graphical boards
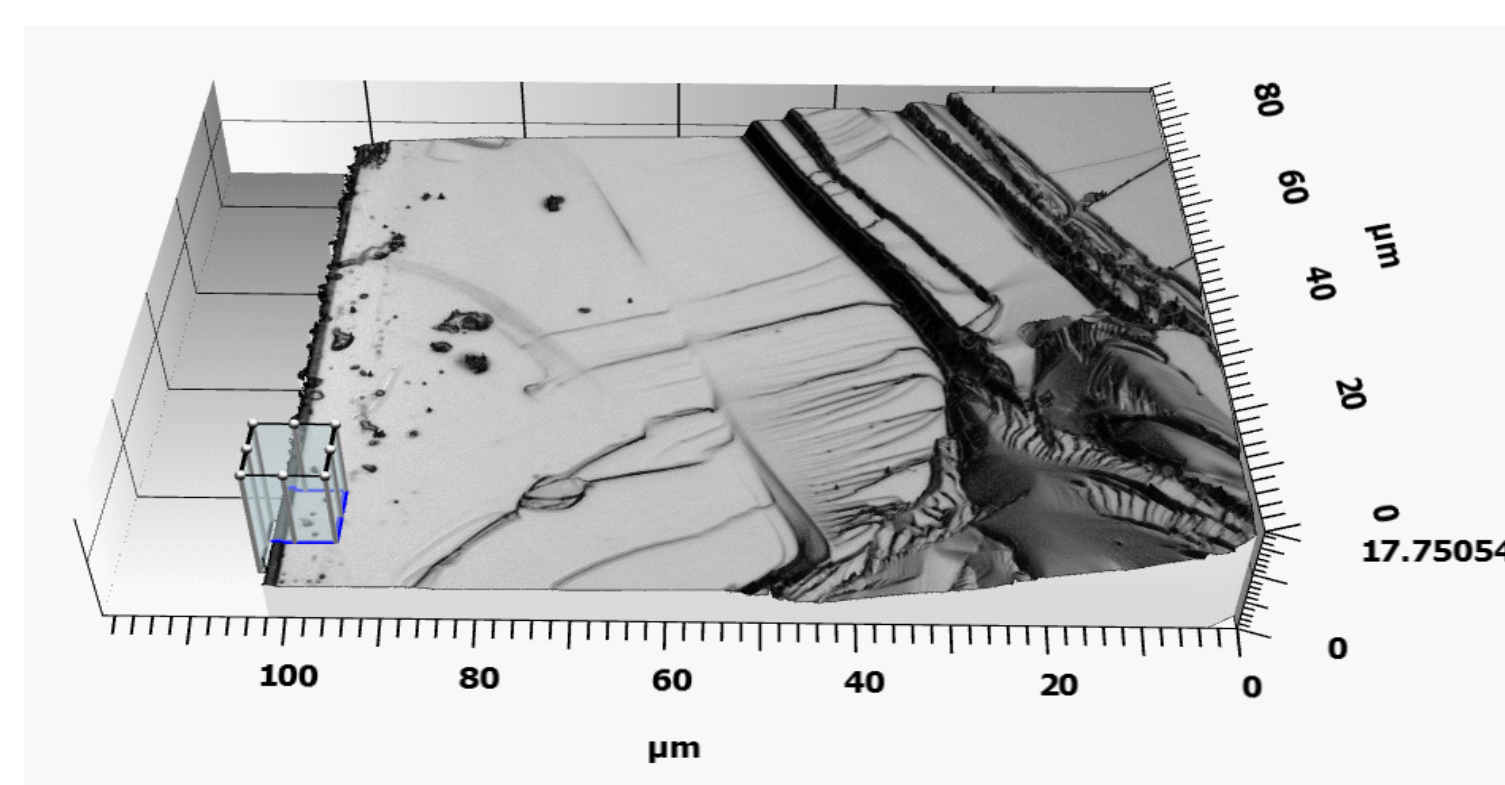
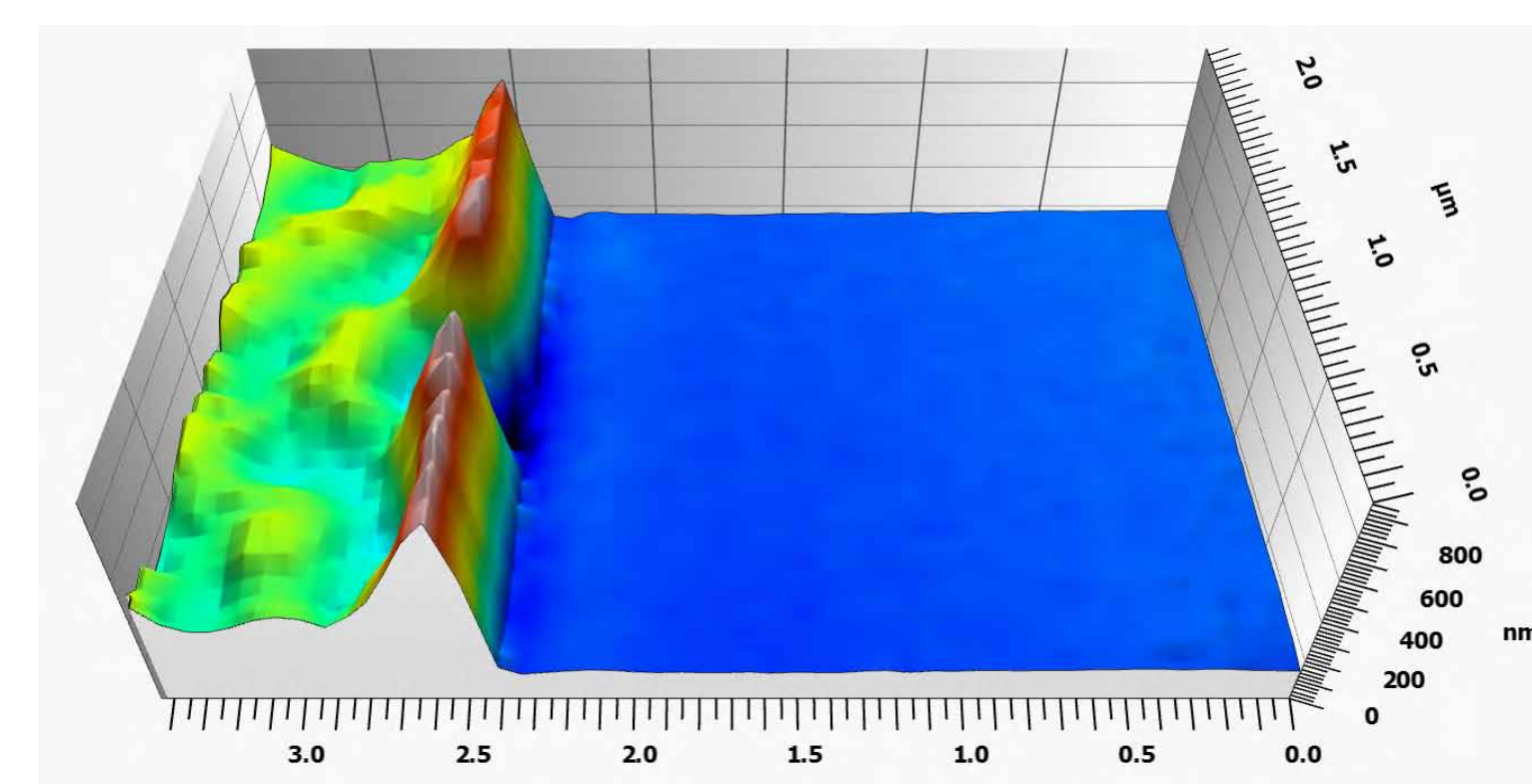## smartWLI resolves details below the rayleigh limit

SEM (scanning electron microscopy)

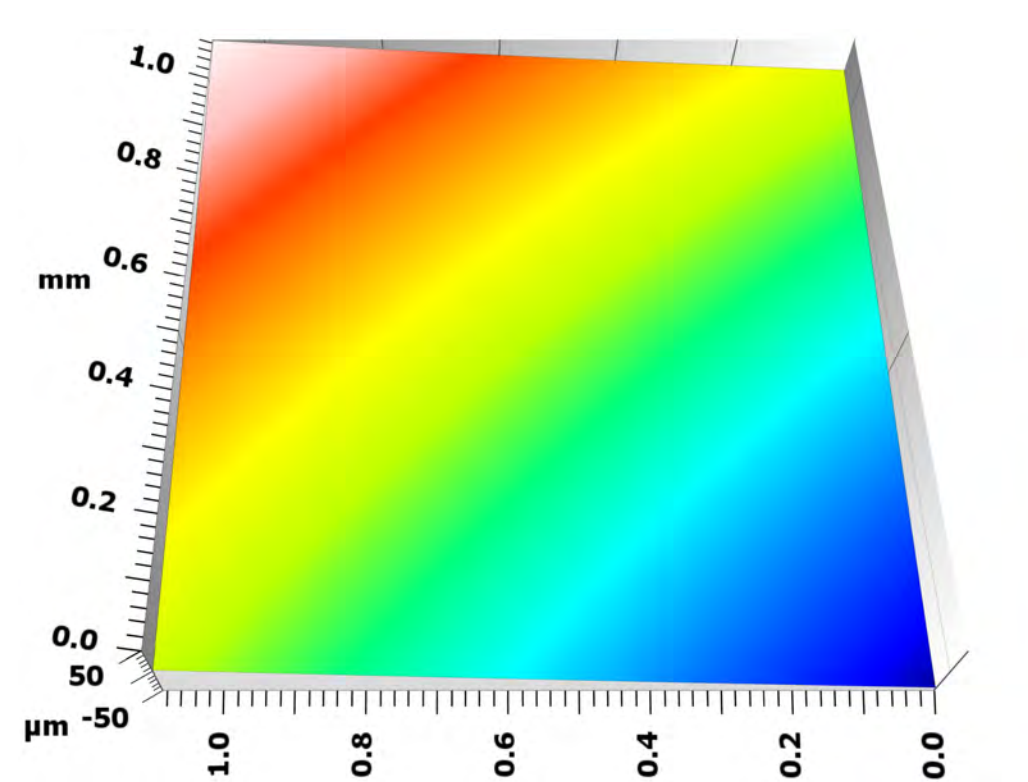100x objective / similar area as SEM
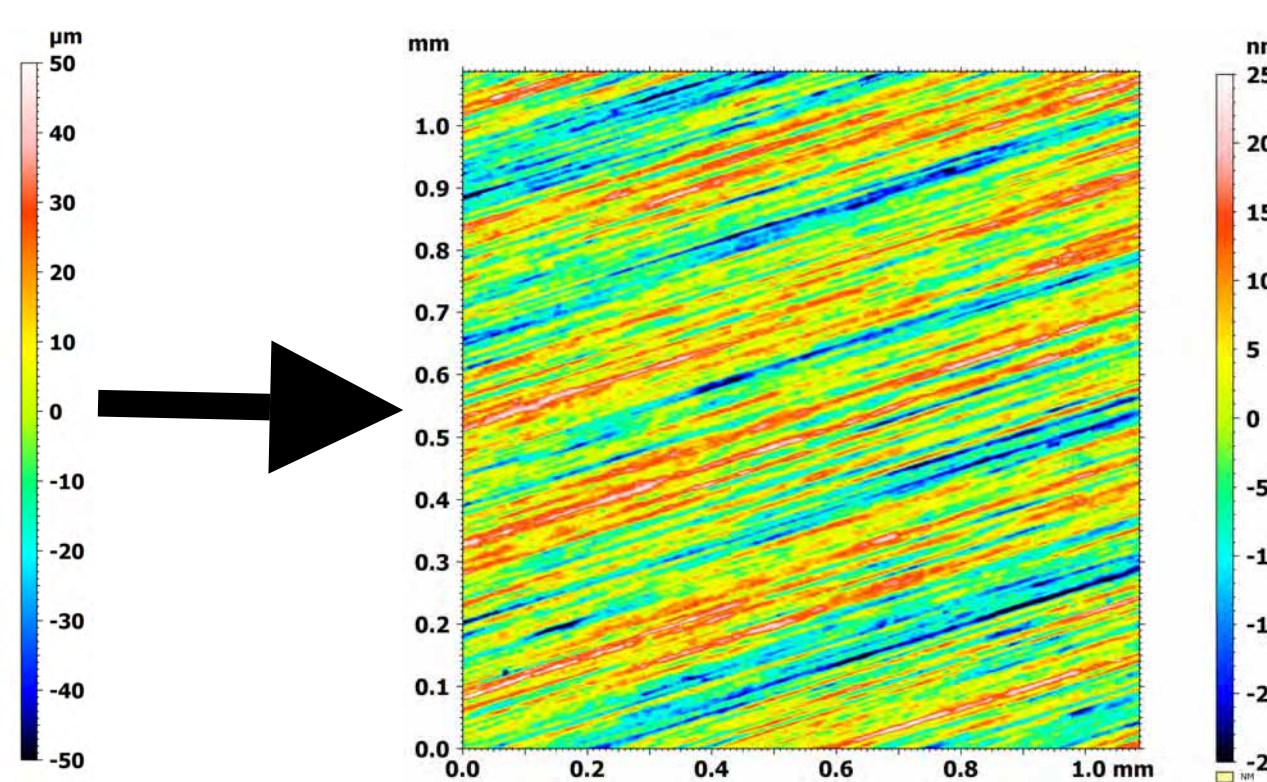
3d image smartWLI 100x full scan

WLI scan / similar area as SEM

smartWLI needs less contrast and provides more object information as microscopic images
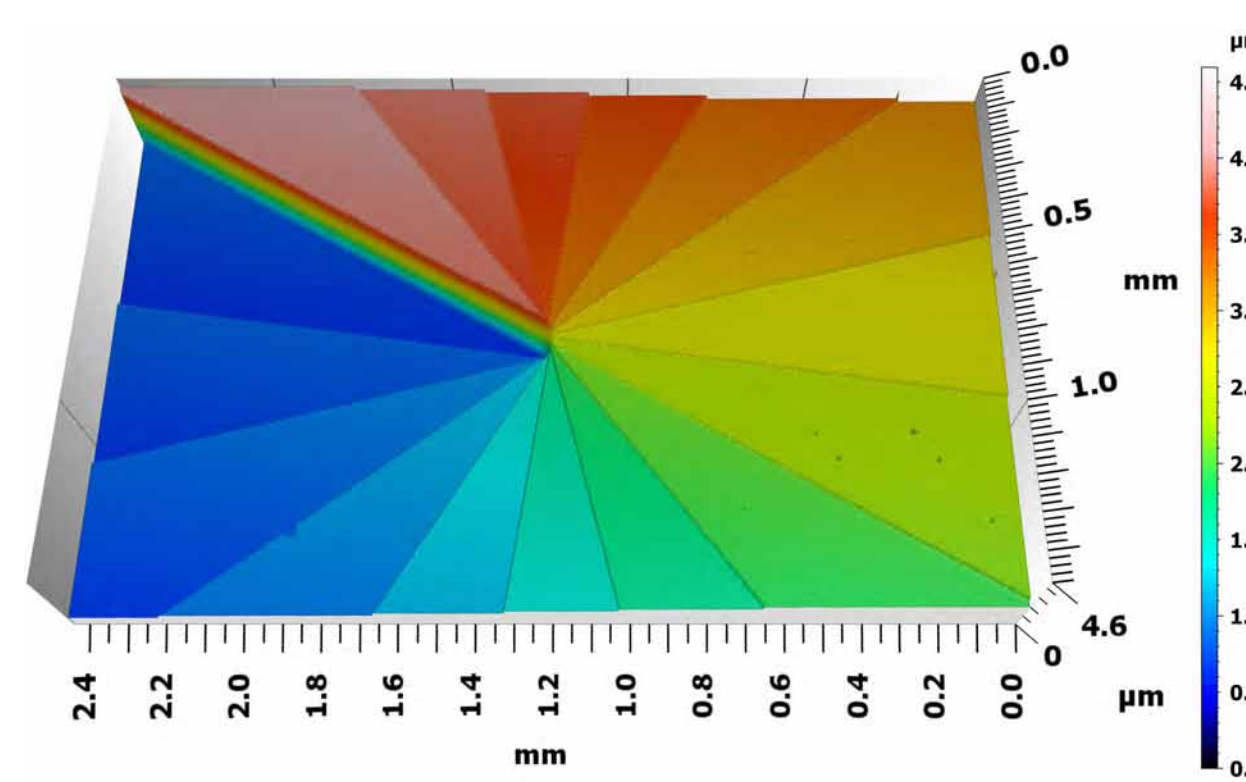
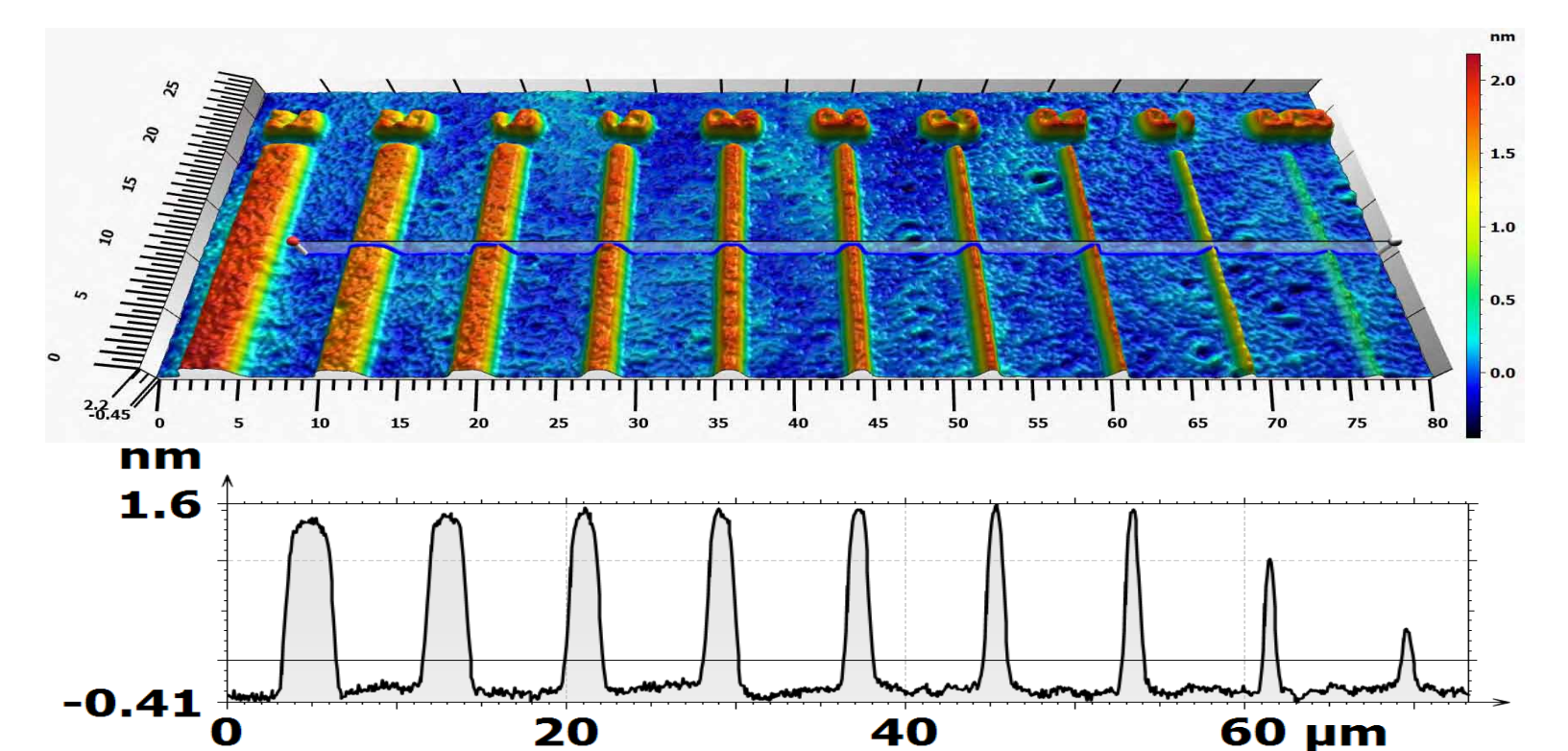## EPSI (extended phase shift interferometry) for sub nanometer resolution

inclined surface of a lens

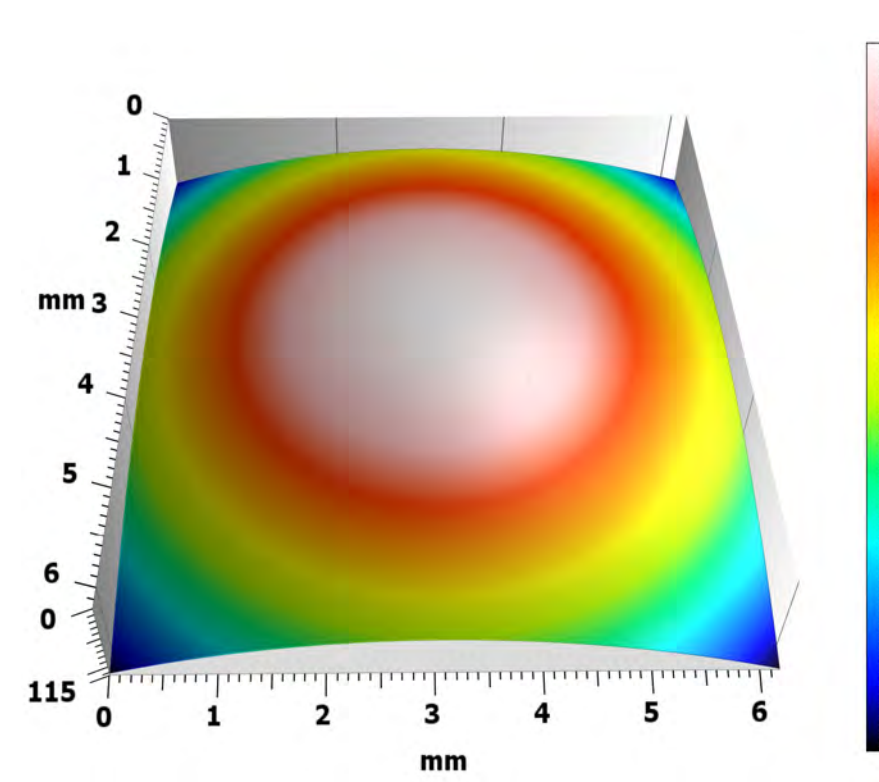surface after form filtering

test structure with small steps

lines down to a thickness of 0.1 μm

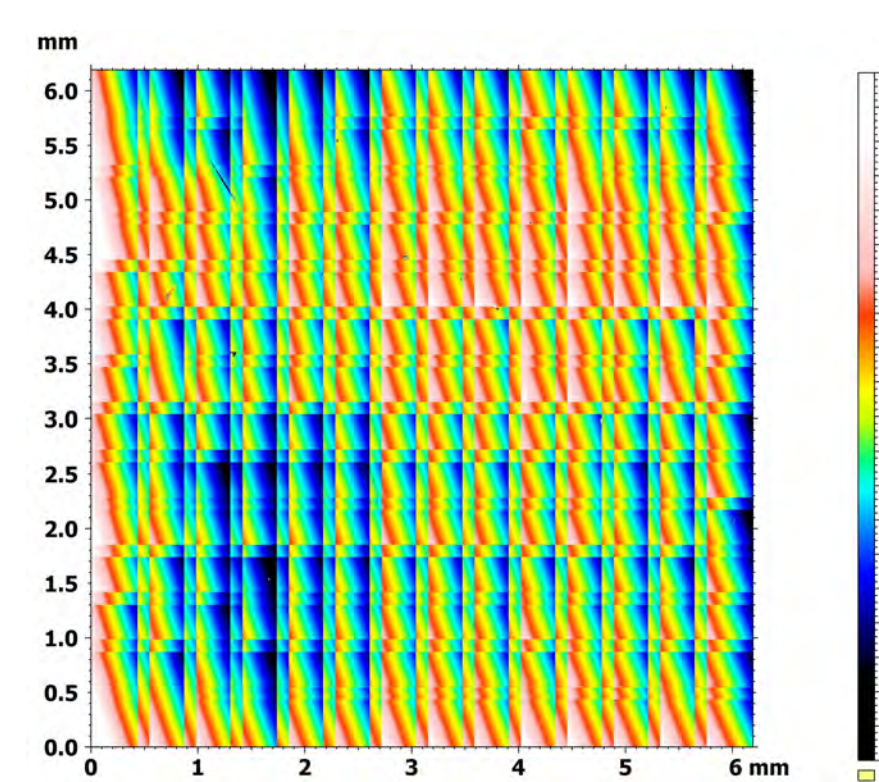EPSI provides sub nanometer resolution on an extended scanning range

smartSTITCH eliminates the limitation of mechanical positioning systems
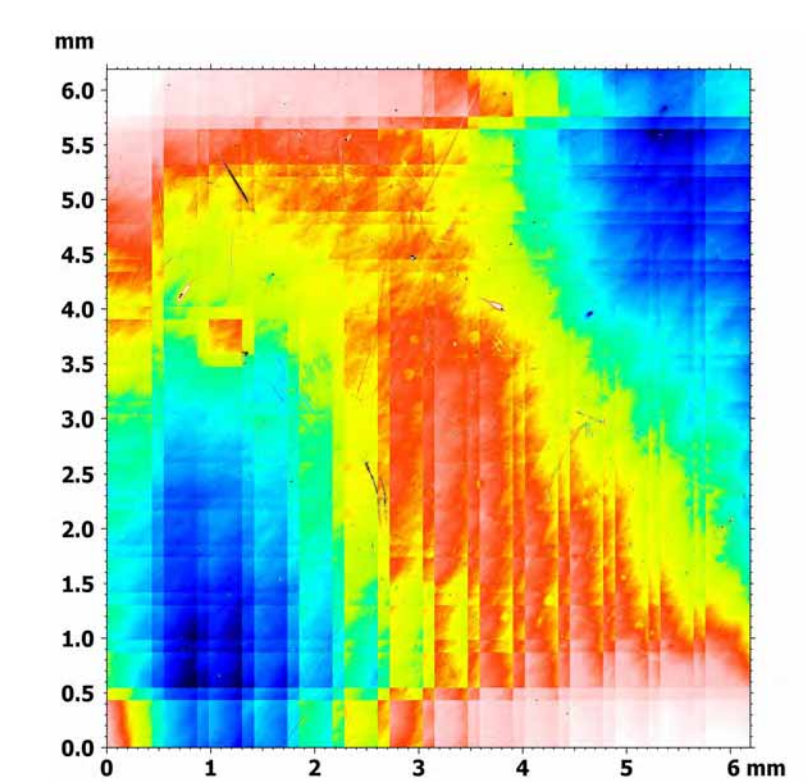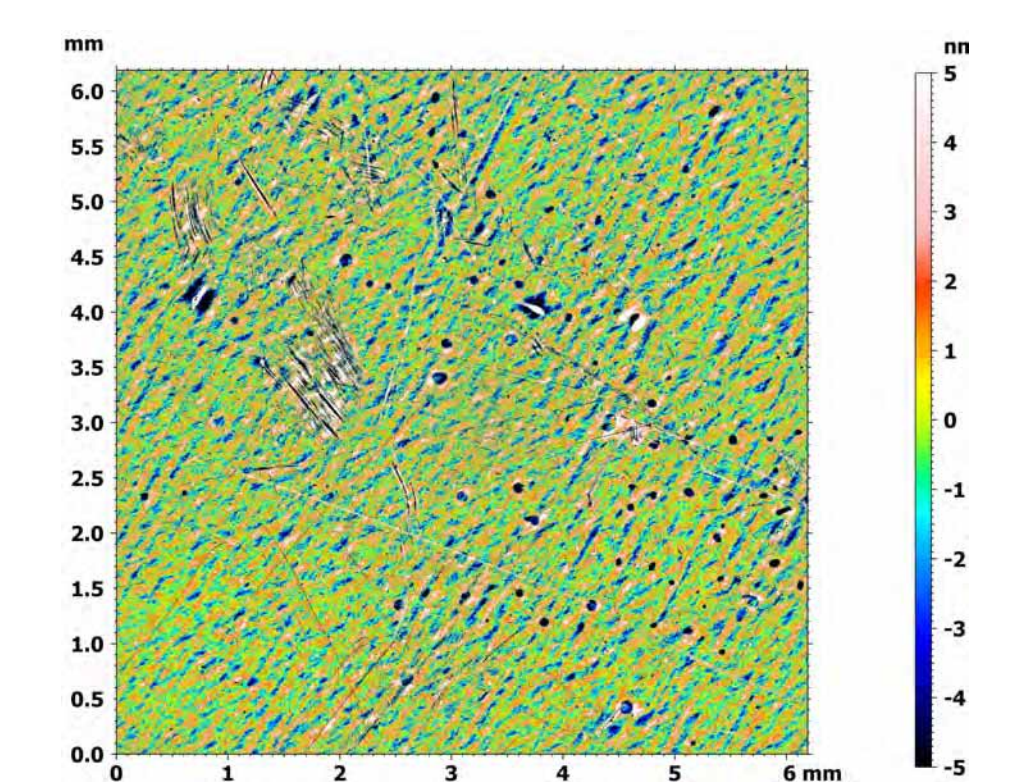

historical magnifying glass
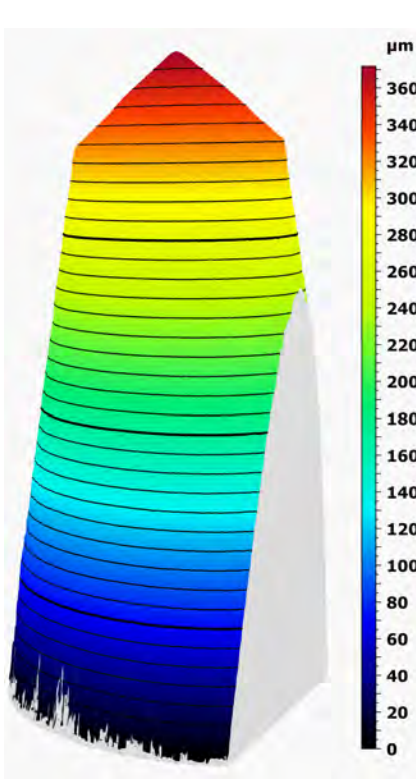
3D scan

full z error of the xy-stage
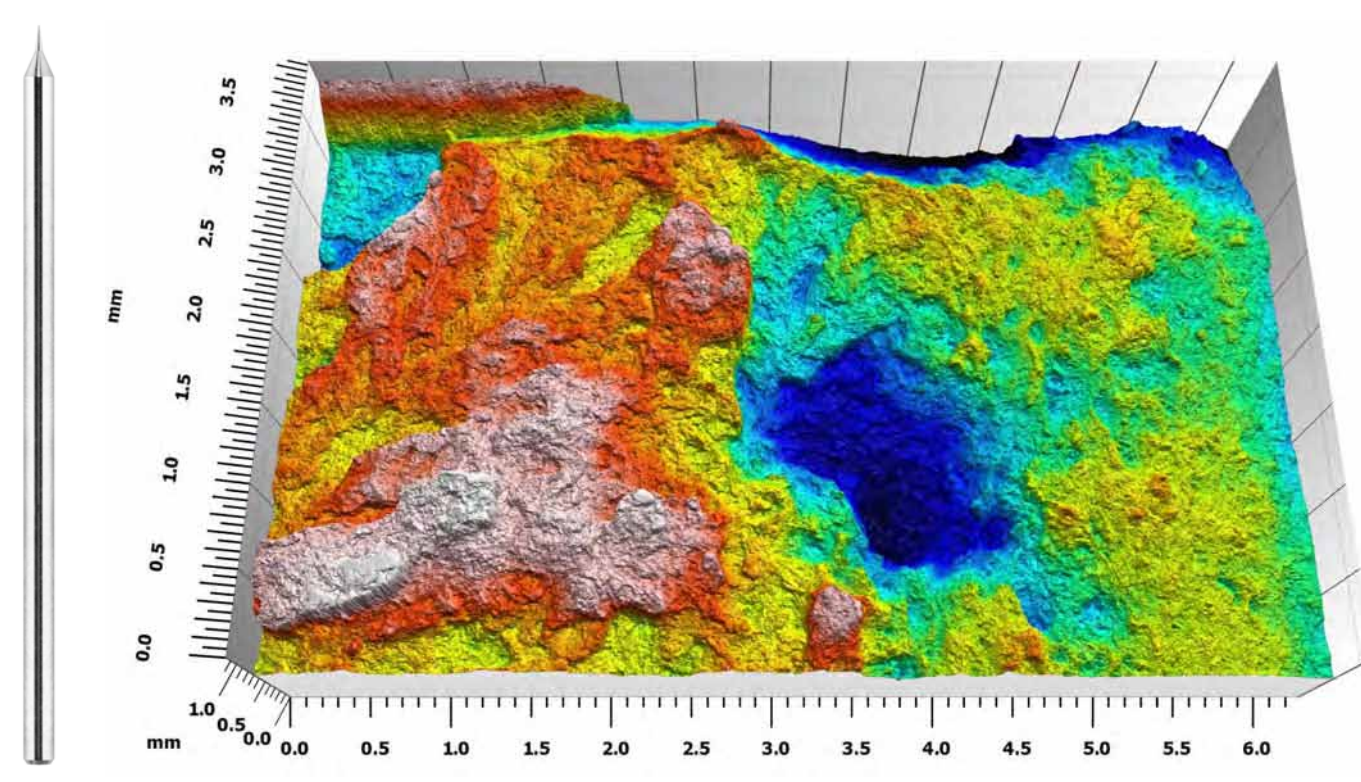
z correction (MountainsMap)

z and angle correction smartSTITCH (GBS)

algorithms for z and angle correction allow the evaluation of nano form deviations and nano structures in larger areas
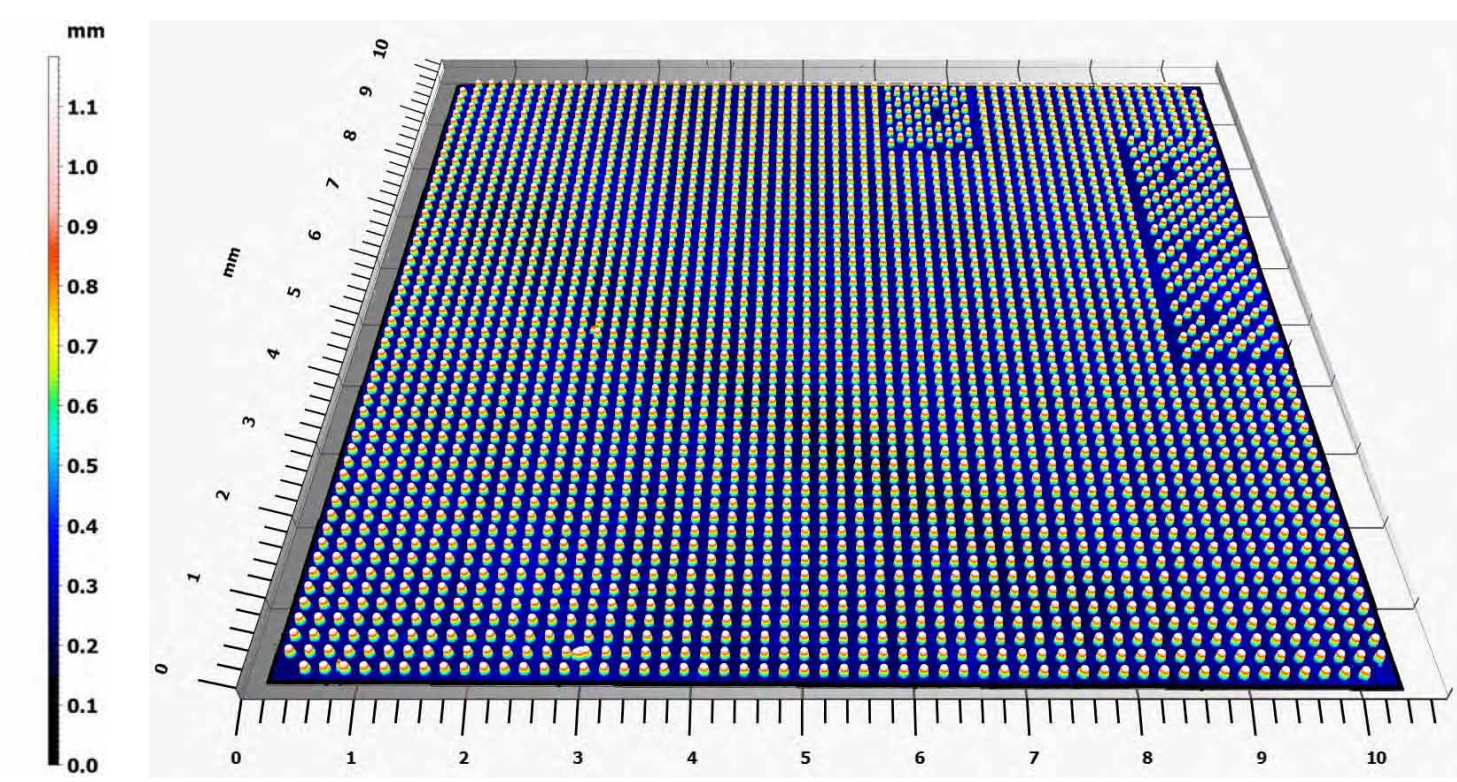
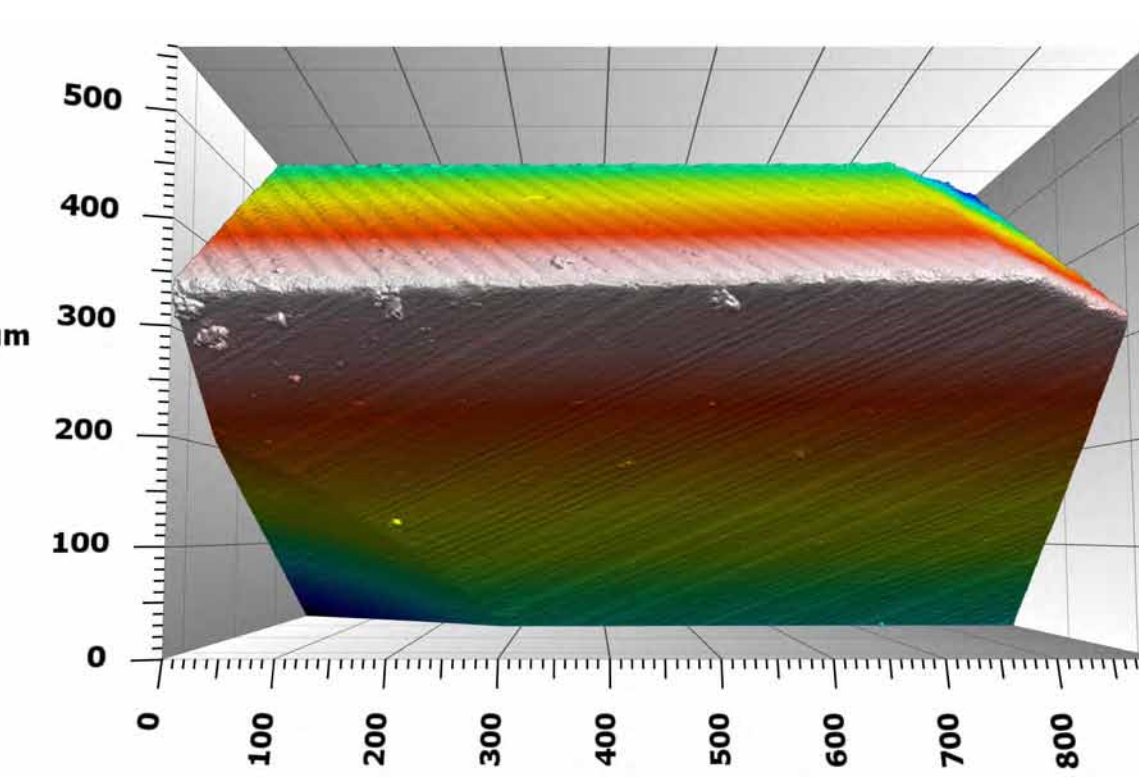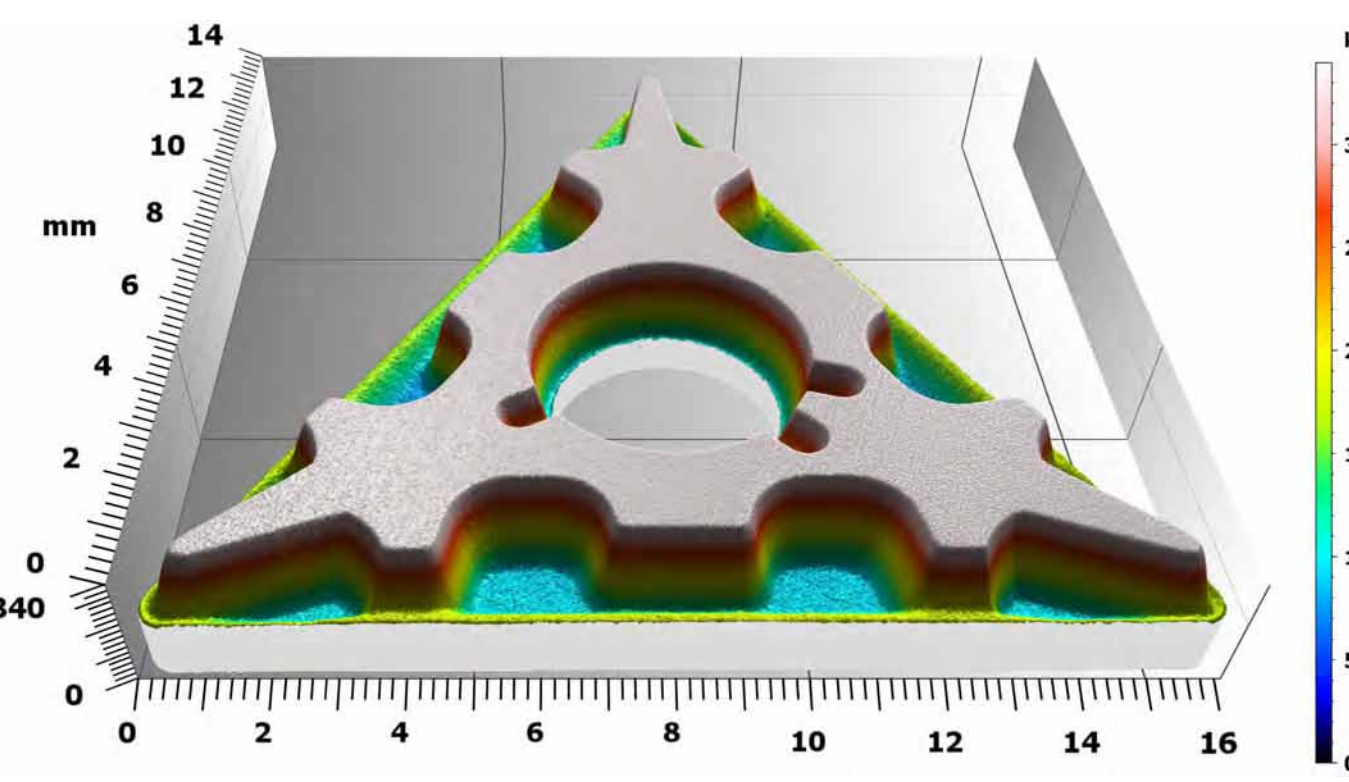## measurements of strongly inclined large objects

needle tip

crack area

solder points

cutting edge, end mill

insert